

PETRI NET-BASED SCHEDULING OF TIME CONSTRAINED SINGLE-ARM CLUSTER TOOLS WITH WAFER REVISITING

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CROSS-REFERENCE TO RELATED APPLICATIONS

[0002] This application claims the benefit of U.S. Provisional Patent Application No. 62/221,028, filed on Sep. 20, 2015, which is incorporated by reference herein in its entirety.

FIELD OF THE INVENTION

[0003] The present invention relates to a method for scheduling time constrained single-arm cluster tools with wafer revisiting.

BACKGROUND

[0004] The following references are cited in the specification. Disclosures of these references are incorporated herein by reference in their entirety.

LIST OF REFERENCES

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